

U.S. Department of Commerce, Patent and Trademark Office	Atty Doc. No.	Application No.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	TNCR.181US0	09/639,495
	Applicant(s)	Confirmation No.
	Mehrdad Nikoonahad, et al.	Unknown
	Filing Date	Group
	August 14, 2000	2878

## U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AD						
	AE						
	AF						
	AG						
	AI						
	AJ						
	AD						
	AE						
	AF						
	AG						
	AK						
	AD						
	AE						
	AG						
	AH						
	AI						

## Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

R2	AQ	R. Pforr, et al., "In-Process Image Detecting Technique For Determination Of Overlay, And Image Quality For ASM-L Wafer Stepper", SPIE Vol. 1674 Optical/Laser Microlithography V (1992) pp. 594-608
Examiner	R2	Date Considered 8/13/03

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.